Author Index of Volume A36

Andrews, M.K., 79, 219 Arshak, K., 73

Baltes, H., 65 Barnett, C.F., 173 Bhatnagar, Y.K., 233 Blythe, S., 1

Cho, S.T., 47 Conedara, V., 241

Dutartre, D., 241

Garcia-Valenzuela, A., 199 Giesler, T., 113 Goebel, H., 227 Goudena, E.J.G., 139 Grattan, K.T.V., 105

Han Guochen, 177 Harris, I.M., 79, 219 Harris, P.D., 219 Hechtenberg, V., 187 Heerens, W.Chr., 37 Holman, A.E., 37 Huang, R.-S., 209 Huijsing, J.H., 157 Iwata, K., 127

Jeanjean, P., 241

Kalandadze, G.I., 43 Karumidze, G.S., 43 Kervalishvili, P.J., 43 Kiełczyński, P., 97 Kihl, H., 29 Kissinger, G., 149 Kissinger, W., 149 Koumoto, K., 121 Krötz, G., 187 Kulozik, M., 227

Langheinrich, W., 227 Laskar, A.S., 1 Lavrenčič, B.B., 167 LeComber, P.G., 173 Legner, W., 187

Manku, T., 193 Mehregany, M., 249 Meyer, J.-U., 113 Miyayama, M., 121 Müller, G., 187 Nakagawa, M., 127 Nanver, L.K., 139 Nathan, A., 193, 233

Odeberg, H., 89 Ohara, Y., 121 Ohishi, H., 127

Pajewski, W., 97 Palmer, A.W., 105 Pan Jian, 177, 183 Perrem, R., 73 Petrík, S., 133 Phillips, S.M., 249 Pruski, A., 29

Rademaker, G., 157 Riedijk, F.R., 157 Rigby, G.A., 209 Robert, J.L., 241 Rose, M.J., 173 Ruan Shunling, 183

Schmiedgen, R., 187 Shalamberidze, S.O., 43 Shavelashivili, Sh.Sh., 43 Sicart, J., 241 Sims, G.E., 173 Snell, A.J., 173 Tabib-Azar, M., 199 Tamada, T., 127 Thureau, P., 57 Tuinstra, F., 37 Turner, G.C., 79, 219

Uchida, H., 127 Utsunomiya, K., 127

van Zeiji, H.W., 139 Völklein, F., 65

Wada, T., 127 Weir, K., 105 Wind, J., 187 Wise, K.D., 47

Xu, Y.-P., 209

Yamamoto, I., 127 Yanagida, H., 121 Yang Tao, 177 Yoshimura, H., 127 Yuan Libo, 177, 183 Yupapin, P.V.P., 105

Žigon, B., 167 Zucker, O., 227

Subject Index of Volume A36

Accelaration sensor

design for; PZT-polymer piezoelectric composites, 121

colour detection using amorphous semiconductor thin-film, 187

Analog-to-digital converter

dual-bit low-offset sigma delta, for integrated smart sensors, 157

Anisotropic etching

of (100) Si, pyramidal protusions in, 233

Automatic compensation

fiber-optic differential pressure sensor, 183

Bar-code reading

new amorphous Si reflective sensor optimized for, 173

in vivo measurement of spatial dose distribution around radioactive sources using thermoluminescent BaSO₄:Eu sheet, 127

BIFET process

DIMES-01, baseline, for smart sensor experimentation, 139 Bismuth

fabrication of thin-film strain-gauge transducer using Bi₂O₃-V₂O₅, 73

Bond strengthening

void-free Si-wafer, in 200-400 °C range, 149

Boron

electrical and piezoresistive properties of B-implanted ZMR-SOI films, 241

Built-in selftest

high-performance microflowmeter with, 47

Capacitive detection

electrostatic excitation and, of flexural plate-waves, 113 Capacitive sensors,

using, for in situ calibration of displacements in piezodriven translation stage of STM, 37

Colour detection

using amorphous semiconductor thin-film alloys, 187

Compensation mechanism

analysis of, of fiber-optic displacement sensor, 177

Detector performance

pyroelectric thin-film, 167

DIMES-01

baseline BIFET process for smart sensor experimentation, 139

Displacement sensor

analysis of compensation mechanism of fiber-optic, 177 based on speckle detection with 0.1 nN and 0.1 Å resolution, fiber-optic force and, 199

Electrical properties

of boron-implanted ZMR-SOI films, 241

Electrostatic excitation

and capacitive detection of flexural plate-waves, 113

Epoxy multichip modules

solution to problem of packaging and interconnection of sensors and signal-processing chips, 1

Europium

in vivo measurement of spatial dose distribution around radiactive sources using thermoluminescent BaSO₄:Eu sheet, 127

Fiber-optic differential pressure sensor

automatic compensation, 183

Fiber-optic displacement sensor

analysis of compensation mechanism of, 177

Fiber optic force and displacement sensor

based on speckle detection with 0.1 nN and 0.1 Å resolution, 199

Flexural plate-waves

electrostatic excitation and capacitive detection of, 113

Fluxmeters

new thermal, using particular auxiliary walls and zerobalanced methods of measurement, 57

Force sensor

fiber-optic, and displacement based on speckle detection with 0.1 nN and 0.1 Å resolution, 199

Gas

resonant pressure sensor based on squeezed film of, 219

effect of rotor slip on, of harmonic side-drive micromotors, 249

Harmonic side-drive micromotors

effect of rotor slip on gear ratio of, 249

Hysteresis

shape memory alloy, 29

Infrared detection

using thermally isolated Si diode, 209

Low-coherence light source

optical pressure sensor using, with photoelastic sensing element, 105

Magnetometers

proposal of optimal optical-fiber coating for interferometric optical-fiber, 133

Microflowmeter

high-performance, with built-in self test, 47

Micromotors

effect of rotor slip on gear ratio of harmonic side-drive, 249

Microsensors

optimization tool for performance parameters of thermoelectric, 65

Microstructure

comparison of squeeze-film theory with measurements on,

Neutrons

semiconductor sensor for, 43

Optical-fiber coating

for interferometruc optical-fiber magnetometers, proposal of, 133

Optical pressure sensor

using low-coherence light source with photoelastic sensing element, 105

Oxygen plasma processing

application of, to Si direct bonding, 227

Packaging

epoxy multichip modules; solution to problem of, and interconnection of sensors and signal-processing chips, 1

Photoelastic sensing element

optical pressure sensor using low-coherence light source with, 105

Piezo-driven translation stage

of STM, using capacitive sensors for in situ calibration of displacements in, 37

Piezoresistive properties

of boron-implanted ZMR-SOI films, electrical and, 241

Pressure sensor

automatic compensation fiber-optic differential, 183 resonant, based on squeezed film of gas, 219

Pyramidal protrusions

in anisotropic etching of (100) Si, 233

Pyroelectric thin-film detector

performance, 167

PZT-polymer piezoelectric composites design for acceleration sensor, 121

Radioactive sources

in vivo measurement of spatial dose distribution around, using thermoluminescent BaSO₄:Eu sheet, 127

Reflective sensor

new amorphous Si, optimized for bar-code reading, 173 Rotor slip

effect of, on gear ratio of harmonic side-drive micromotors, 249

Semiconductor sensor

for neutrons, 43

Semiconductor thin-film alloys

colour detection using amorphous, 187

Sensor opinions

using recursive least squares to form, 89

Shape memory alloy hysteresis, 29

Signal-processing chips

expoxy multichip modules; solution to problem of packaging and interconnection of sensors and, 1 Silicon

application of oxygen plasma processing to Si direct bonding, 227

infrared detection using thermally isolated Si diode, 209

new amorphous Si reflective sensor optimized for bar-code reading, 173

pyramidal protrusions in anisotropic etching of (100) Si,

void-free Si-wafer-bond strengthening in 200-400 °C range, 149

Silicon direct bonding

application of oxygen plasma processing to, 227

Silicon-on-insulator

electrical and piezoresistive properties of boron-implanted ZMR-SOI films, 241

Smart sensor experimentation

DIMES-01, baseline BIFET process for, 139

Smart sensors

dual-bit low-offset sigma delta analog-to-digital converter for integrated, 157

Spatial dose distribution

around radioactive sources, in vivo measurement, using thermoluminescent BaSO₄:Eu sheet, 127

Speckle detection

fiber-optic-force and displacement sensor based on, with 0.1 nN and 0.1 Å resolution, 199

Squeeze-film theory

comparison of, with measurements on microstructure,

Strain-gauge transducer

fabrication of thin-film, using Bi₂O₃-V₂O₅, 73

Temperature fields

analysis of, in ultrasonic transducers of high power, 97 Thermal fluxmeters

new, using particular auxiliary walls and zero-balanced methods of mesurement, 57

Thermoelectric microsensors

optimization tool for performance parameters of, 65

Thermomagnetic carrier transport equation, 193

Transport equation

thermomagnetic carrier, 193

Ultrasonic transducers

of high power, analysis of temperature fields in, 97

Vanadium

fabrication of thin-film strain-gauge transducer using $Bi_2O_3-V_2O_5$, 73

Zone-melt-recrystallized films

electrical and piezoresistive properties of B-implanted ZMR-SOI films, 241

